



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980
Filing Date: July 28, 1999
Applicant: Yasuaki Tsuzuki et al.
Group Art Unit: 1765
Examiner: L. Umez Eronini
Title: Method of Etching Metallic Thin Film on Thin Film Resistor
Attorney Docket: 4041J-000439

Hon. Commissioner of Patents and Trademarks
Washington, D.C. 20231

**PETITION TO CORRECT INVENTORSHIP
UNDER 37 C.F.R. § 1.48(b)**

Dear Sir:

Applicant respectfully requests that the inventorship of the above identified application be corrected pursuant to 37 C.F.R. § 1.48(b). Claims 1-4 have been allowed in this application. Therefore, Ichiro Ito, Satoshi Shiraki, Tomio Yamamoto, Makoto Ohkawa and Atsumi Takahashi should be deleted because their invention is no longer being claimed in the above identified application.

Enclosed is a check for \$130.00 pursuant to 37 C.F.R. § 1.17(i) to cover the fee for this petition.


The Commissioner is hereby authorized to charge any additional fees which may be required to effect this communication or to maintain pendency of this application, or credit any overpayment, to Account No. 08-0750. A duplicate copy of this sheet is enclosed for this purpose.

If the Examiner believes that personal communication will expedite prosecution of this application, the Examiner is invited to telephone the undersigned at (248) 641-1600.

Respectfully submitted,

Dated: April 19, 2002
HARNES, DICKEY & PIERCE, P.L.C.
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By:


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